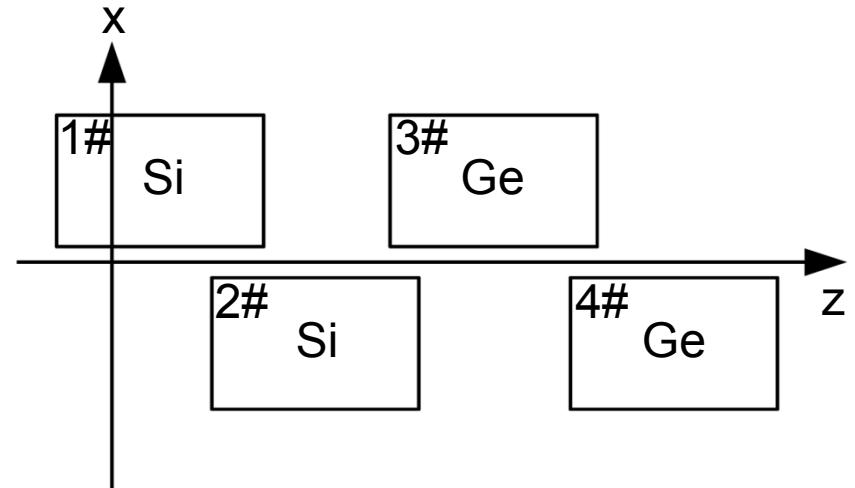
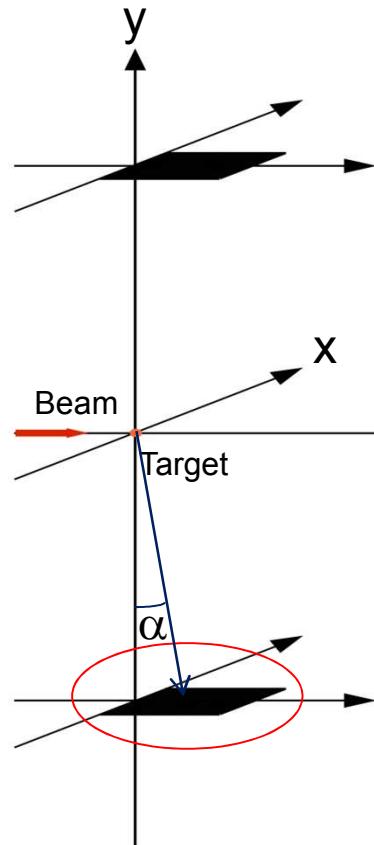




# Si Detectors Test of Day-one Experiment Setup

Q.Hu, J. Ritman, H. Xu

# Introduction of day-one experiment setup

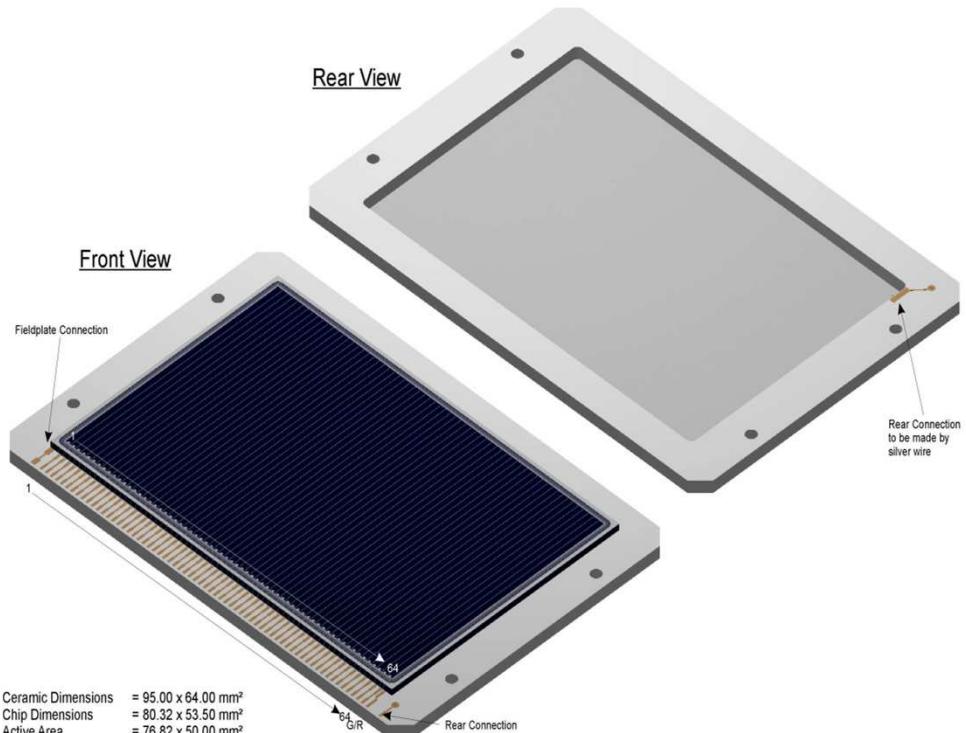


1#, 2#: 76.8 mm\*50.0 mm\*1.0 mm  
 3#, 4#: 80.4 mm\*50.0 mm\*5.0 (11.0) mm

Single sided  
 Pitch: 1.2 mm  
 Si: 400 keV ~ 12 MeV  
 Ge: 12 MeV ~ 60 MeV

Expected energy resolution: ~ 22.5 keV

# Structure of the Si detectors



Ceramic Dimensions: 95.00\*64.00 mm<sup>2</sup>  
 Chip Dimensions: 80.32\*53.50 mm<sup>2</sup>  
 Active Area: 76.82\*50.00 mm<sup>2</sup>

## Si\_1 (Si\_2591-13)

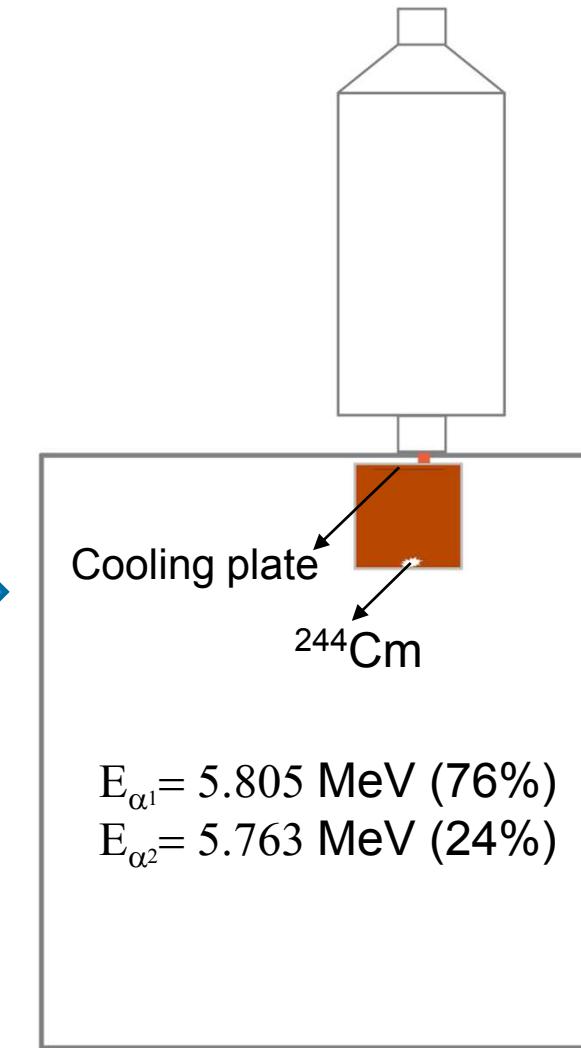
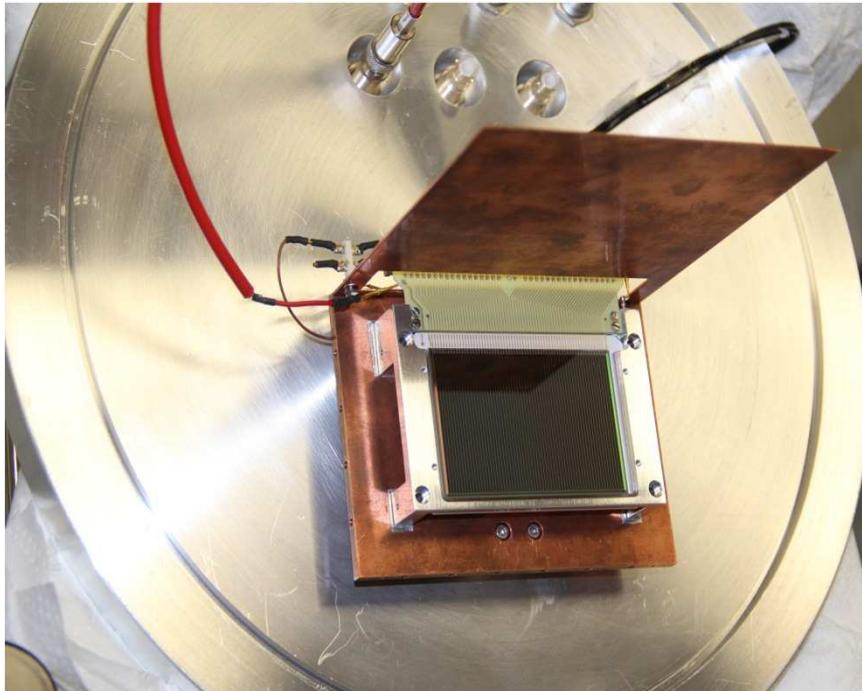
Thickness: 1043 µm  
 Depletion: 65 V

## Si\_2 (Si\_2591-15)

Thickness: 1045 µm  
 Depletion: 52 V

Operating voltage: 200 V (max)  
 Dead layer: < 0.1 µm

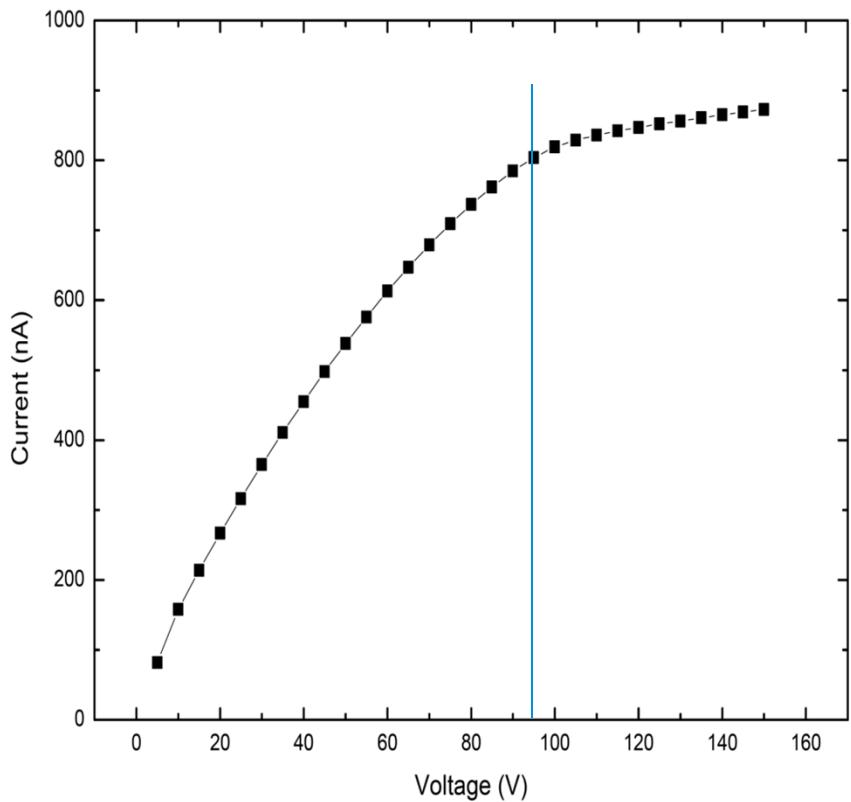
## Test setup & conditions



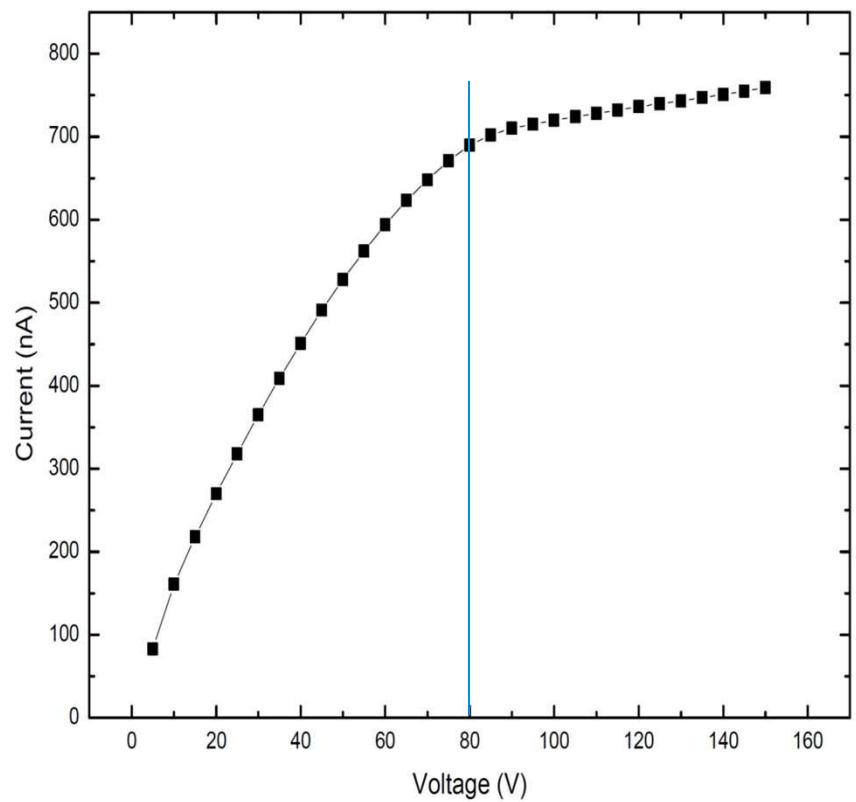
Cooling method:  $\text{LN}_2$   
Vacuum:  $\sim 10^{-7} \text{ mbar}$

## V – I curve @ 299 K

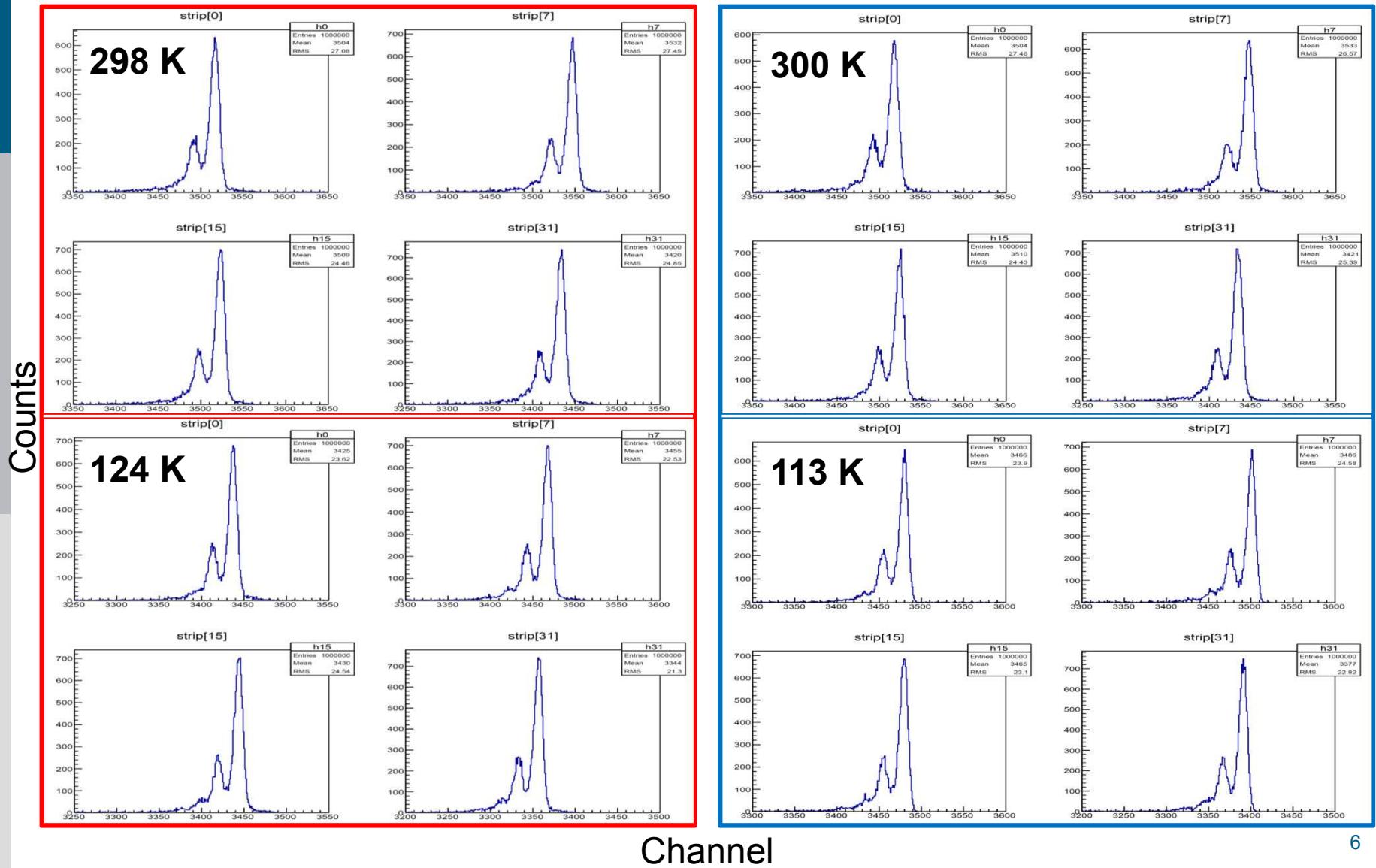
Si\_1



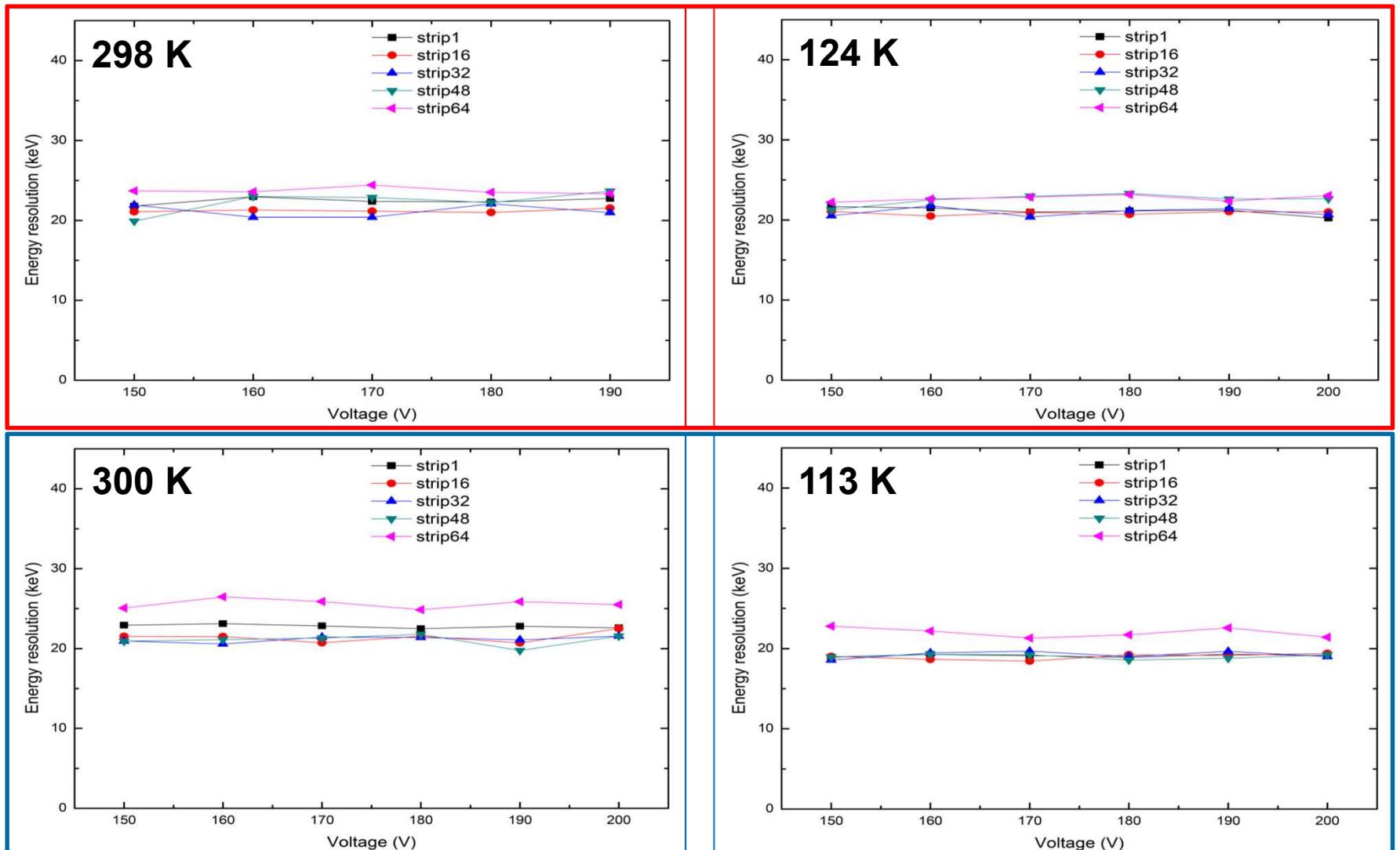
Si\_2



## Energy spectra of the front side (Si\_1 & Si\_2) @ 180 V

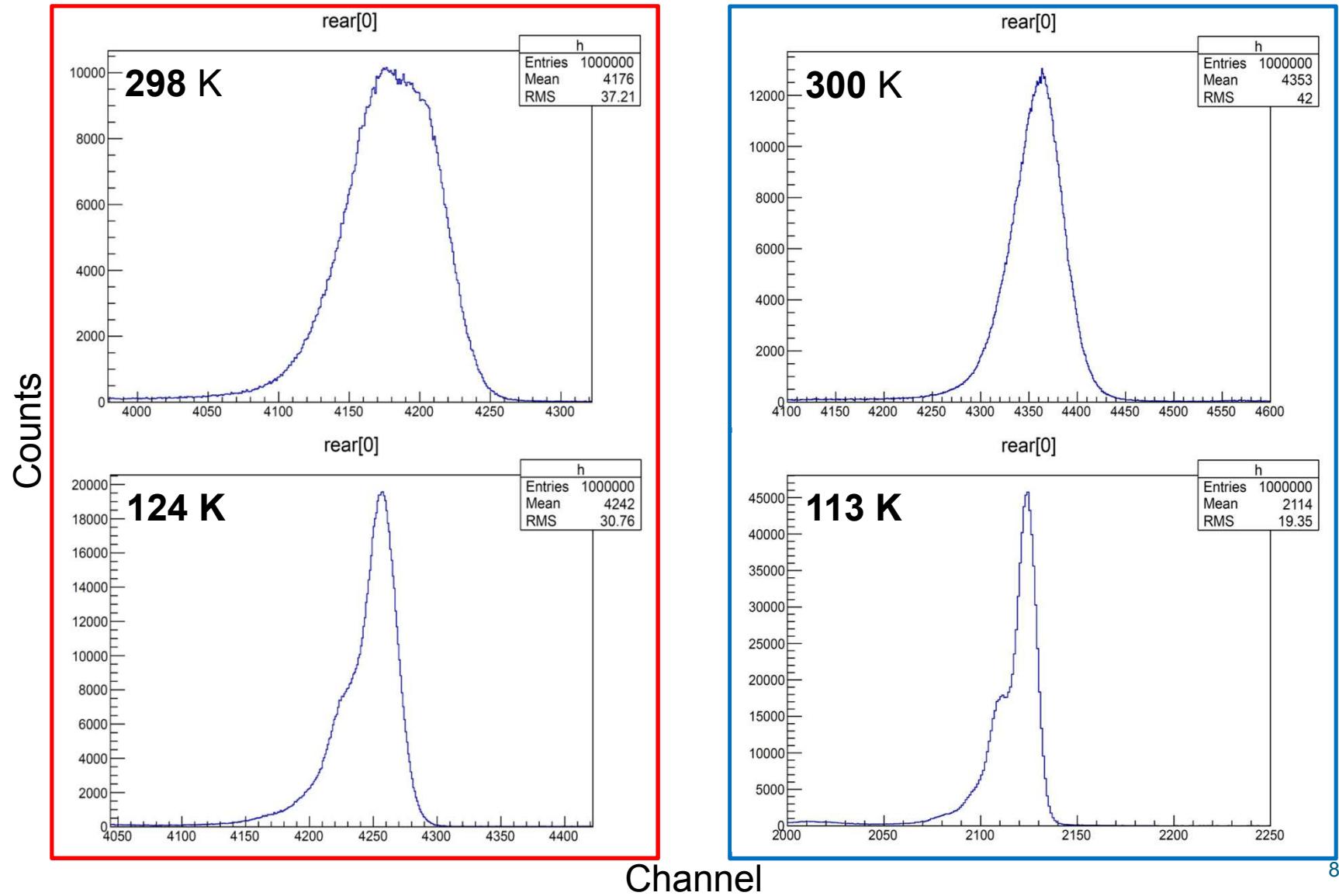


## Energy resolution (FWHM) vs. Voltage (Si\_1 & Si\_2)



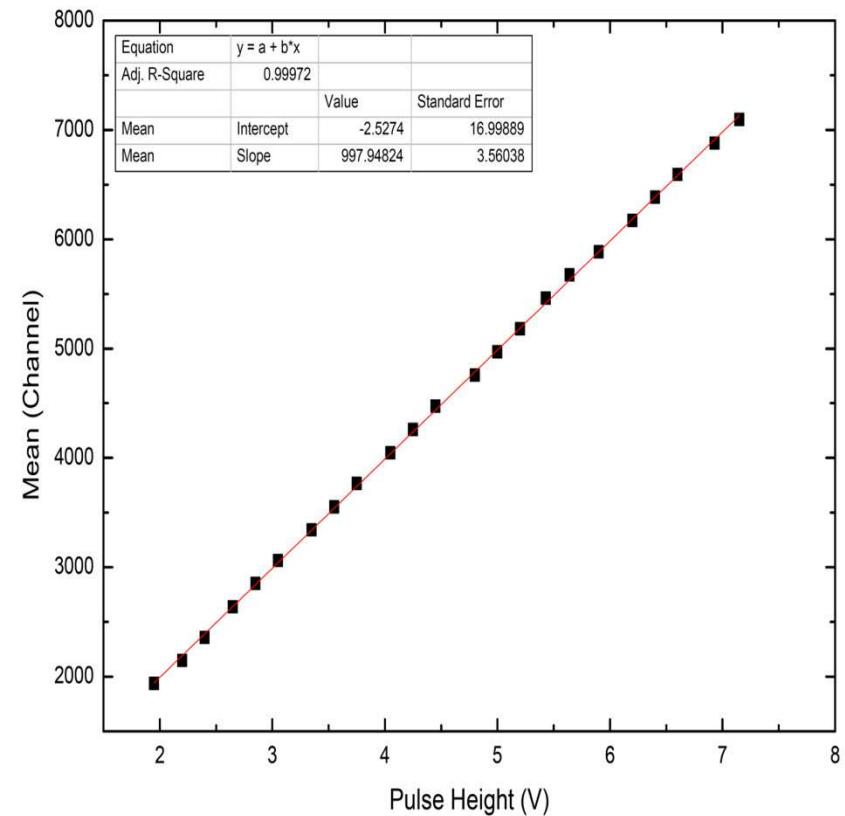
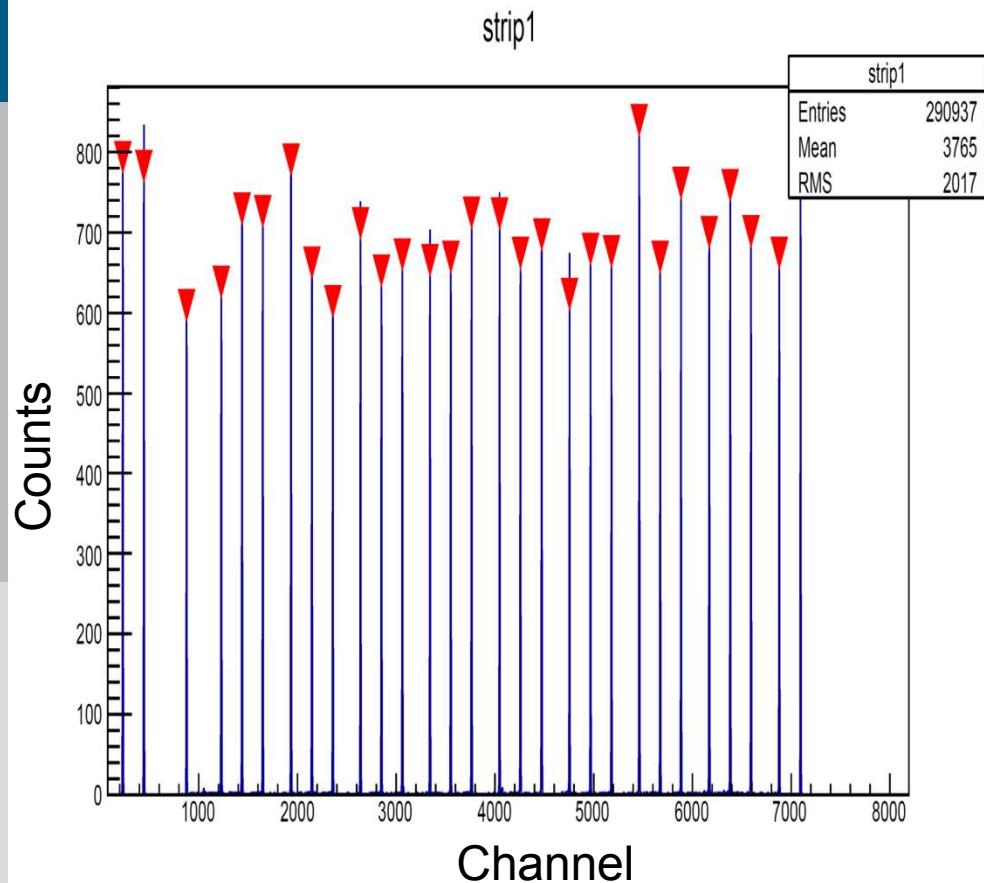
The dead layer has been taken into account.

## Energy spectra of the rear side (Si\_1 & Si\_2) @ 180 V



# Calibration study

Pulse Generator: ORTEC Model 419



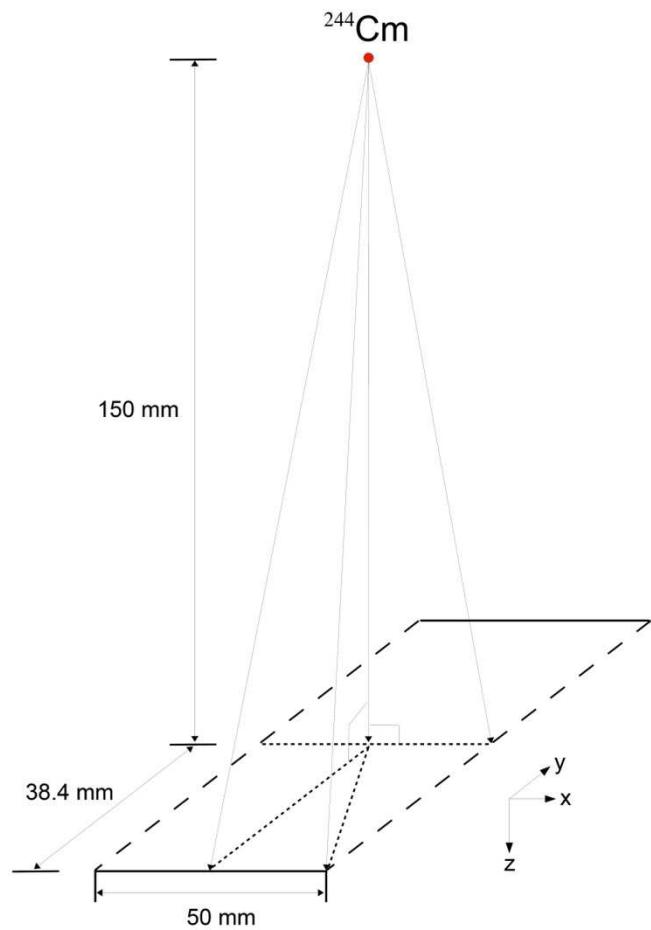
- 1. Linearity; 2. Pedestal.

## Summary

1. The electronics runs well;
2. Si detectors meet our requirement.

## Next step

1. Further test for Ge detectors;
2. Energy calibration;
3. Development of temperature controller.



$$E'_{\alpha 1} = E_{\alpha 1} - E_{1\_loss}$$

$$E'_{\alpha 2} = E_{\alpha 2} - E_{2\_loss}$$

$$\text{FWHM} = 2.355 * \sigma^* (E'_{\alpha 1} - E'_{\alpha 2}) / (\text{Mean}_1 - \text{Mean}_2)$$